

September 15, 2006

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450  
U.S.A.

Re: New Utility Patent Application  
Type: U.S. National Stage application under 35 USC 371  
Atty. Docket No: PA214WP002  
First Inventor: Fumi NABESHIMA  
Assignee: Komatsu Electronic Metals Co., Ltd.  
Title: SEMICONDUCTOR WAFER INSPECTION DEVICE AND  
METHOD

Sir:

With regard to the captioned new utility patent application filed concurrently herewith, please note that this submission contains the following material, in order:

- (1) Utility Patent Application Transmittal Form;
- (2) Fee Transmittal Form and Appropriate Fee;
- (3) Application Data Sheet;
- (4) Specification consisting of 39 pages;
- (5) Drawings consisting of 6 pages;
- (6) Signed Combined Declaration and Power of Attorney (4 pages);
- (7) Assignment of the application (1 page);
- (8) International Search Report; and
- (9) Certified Copy of Priority Document.

Respectfully submitted,

A handwritten signature in dark ink, appearing to read "Joseph P. Farrar", is written over a horizontal line.

Joseph P. Farrar

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JF/so